

(2) Please replace pending claim 1 with the following new claim 1 (APPENDIX 1):

D₁ 1. (third time amended) A wafer conveyance system for transporting one or more wafers that undergo, while being transported, different processes at a plurality of wafer processing apparatuses, each wafer processing apparatus defining a self-contained environment in its inside which provides a controlled atmosphere in which one or more wares are processed, the wafer conveyance system comprising:

- (a) a hermetically closed chamber that provides an isolated environment that is in communication with the inside of each wafer processing apparatus through a passage;
 - (b) at least one guide path provided inside the chamber;
 - (c) at least one mobile element being movable inside the chamber along the guide path to transport one or more wafers from one wafer processing apparatus to another; and
 - (d) at least one arm provided on each mobile element, each arm being accessible to the inside of each wafer processing apparatus through a corresponding passage to load one or more wafers into a wafer processing apparatus and unload the same therefrom.
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